

Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	NOVLP076/NVLS-002858	Unassigned
	Applicant:	
	Hausmann et al.	
	Filing Date	Group
	HEREWITH	Unassigned

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
PD	A1	6,511,539	1/28/03	Raaijmakers	—	—	
↗	A2	6,551,399	1/28/03	Mc Collum Etchason, et al.	—	—	
↓	A3	6,540,838	4/1/03	Sneh, et al.	—	—	
	A4	6,503,330	1/7/03	Sneh, et al.	—	—	
PD	A5	6,551,339	4/22/03	Gavronsky	—	—	
	A6						
	A7						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
PD	B1	WO02/27063	4/4/02	PCT			X	

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
PD	C1	"Atomic Layer Deposition of Metal Oxide Thin Films," A thesis presented by Dennis Michael Hausmann, Harvard University, 186 pages, July 2002.
PD	C2	Hausmann et al., "Rapid Vapor Deposition of Highly Conformal Silica Nanolaminates," Science, Vol. 308, October 2002, 5 Pages
	C3	
	C4	
	C5	
	C6	
Examiner	Date Considered	
PHUC T. DANG	11/18/2004	

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	NOVLP076/NVLS-2858	10/672,309
	Applicant:	
	Hausmann et al.	
	Filing Date	Group
	September 23, 2003	1762

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
PD	A1	6,030,881	02.29.00	Papasouliotis et al.	—	—	
PD	A2	6,335,261	01.01.02	Natzle et al.	—	—	

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
Examiner PHUC T. DANG		Date Considered 11/18/2004

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